

# Formation of Strong Drift Field with Cockcroft-Walton Voltage Multiplier in a High-Pressure Xenon Gas TPC

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for the AXEL Collaboration



# Outline

- Introduction
- Drift Field Cage
- Cockcroft-Walton Voltage Multiplier
- Summary

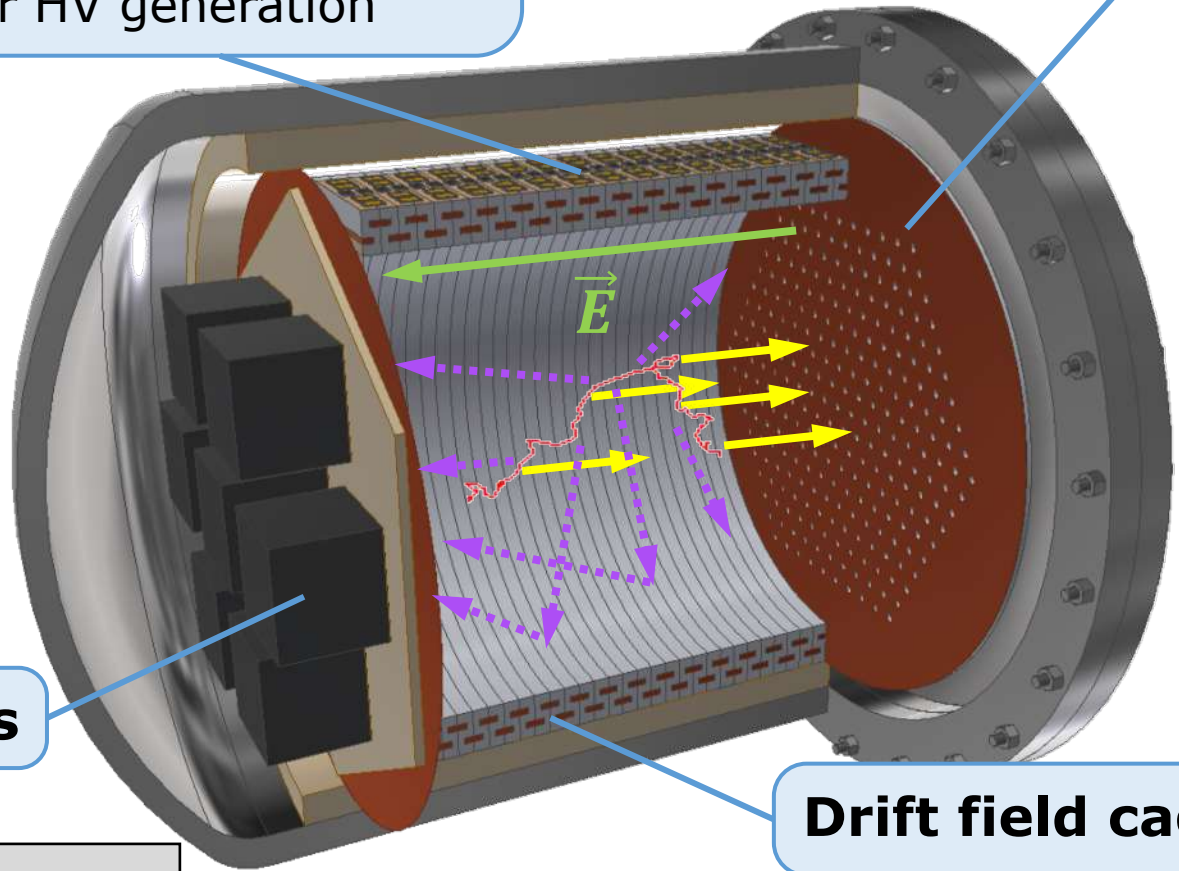
# Introduction

- ✓ AXEL
- ✓ HV Requirements
- ✓ Discharge

# AXEL (A Xenon ElectroLuminescence detector)

**Cockcroft-Walton Voltage multiplier**  
for HV generation

**ELCC**



**VUV PMTs**

**Drift field cage**

- : Drift electrons
- : Scintillation photons

# AXEL (A Xenon ElectroLuminescence detector)



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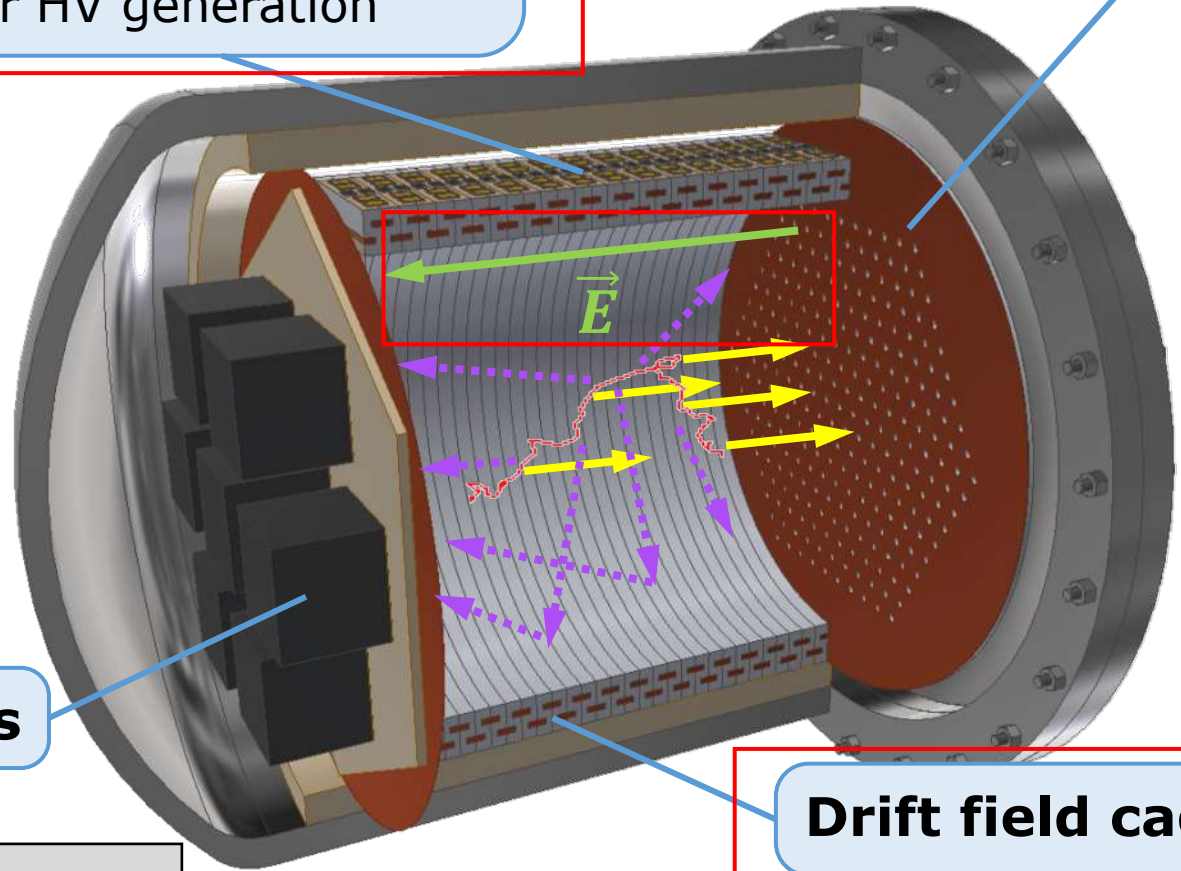
**ELCC**

Topics of this talk

**VUV PMTs**

**Drift field cage**

 : Drift electrons  
 : Scintillation photons



# HV Requirements

EL region:

- EL threshold = **1 kV/cm/atm**
- Higher  $E_{EL}$  → Better electron collection  
Higher EL gain



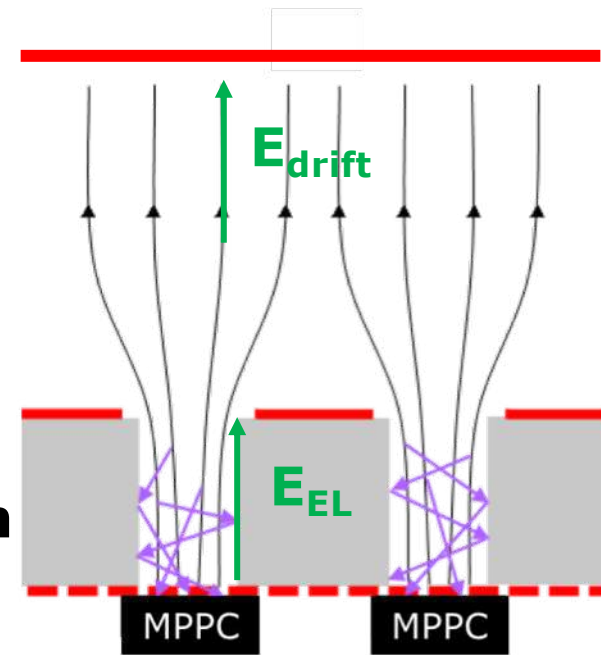
Better **Energy resolution**

Drift region:

- Higher  $E_{drift}$  → Less diffusion  
Less recombination or attachment



Better **Track ID & Energy resolution**



We use  $E_{EL} = 3 \text{ kV/cm/atm}$  &  $E_{drift} = 100 \text{ V/cm/atm}$

# HV R

EL regio

- EL thre
- Higher

Drift reg

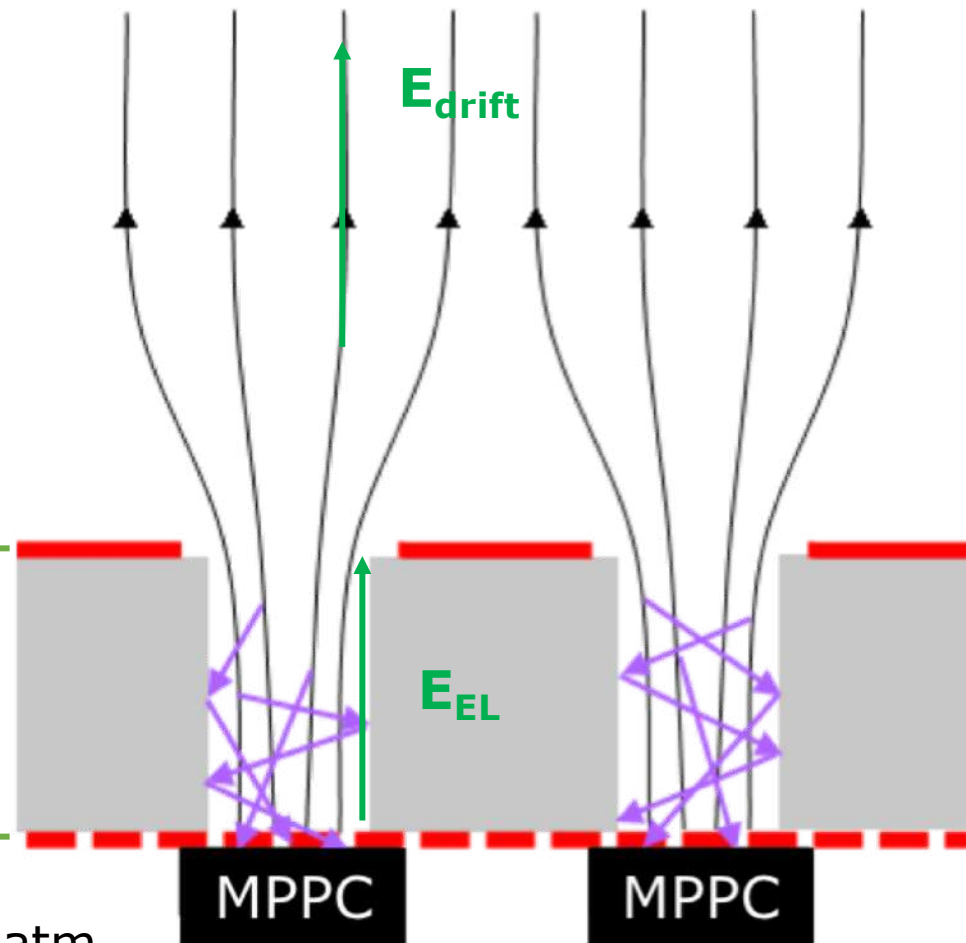
- Higher

$$V_{\text{cathode}} = -65 \text{ kV}$$

$$V_{\text{anode}} = -15 \text{ kV}$$

Ground

for 180L prototype @10 atm



We use  $E_{\text{EL}} = 3 \text{ kV/cm/atm}$  &  $E_{\text{drift}} = 100 \text{ V/cm/atm}$

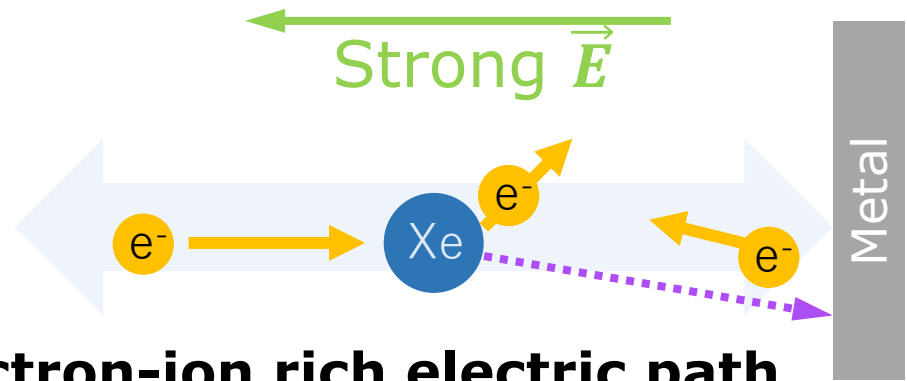
# Discharge

Mechanism:

- $\alpha$  - process
- $\gamma$  - process



**electron-ion rich electric path**



pure xenon gas  $\rightarrow$  Easily ionized, VUV scintillation

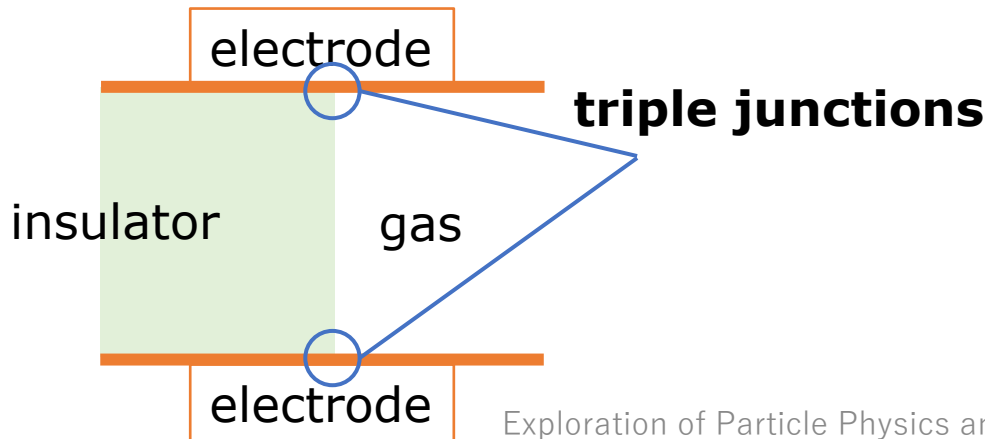
Weak points = strong electric field

✓ **Spikes or Edges on HV electrode**

$\rightarrow$  take distance, round off, or cover by insulator

✓ **Triple junction**

$\rightarrow$  path should be blocked





# Drift Field Cage

- ✓ Requirements
- ✓ Current Design
- ✓ For 180L Full Size

# Requirements

Strong & Uniform Field:

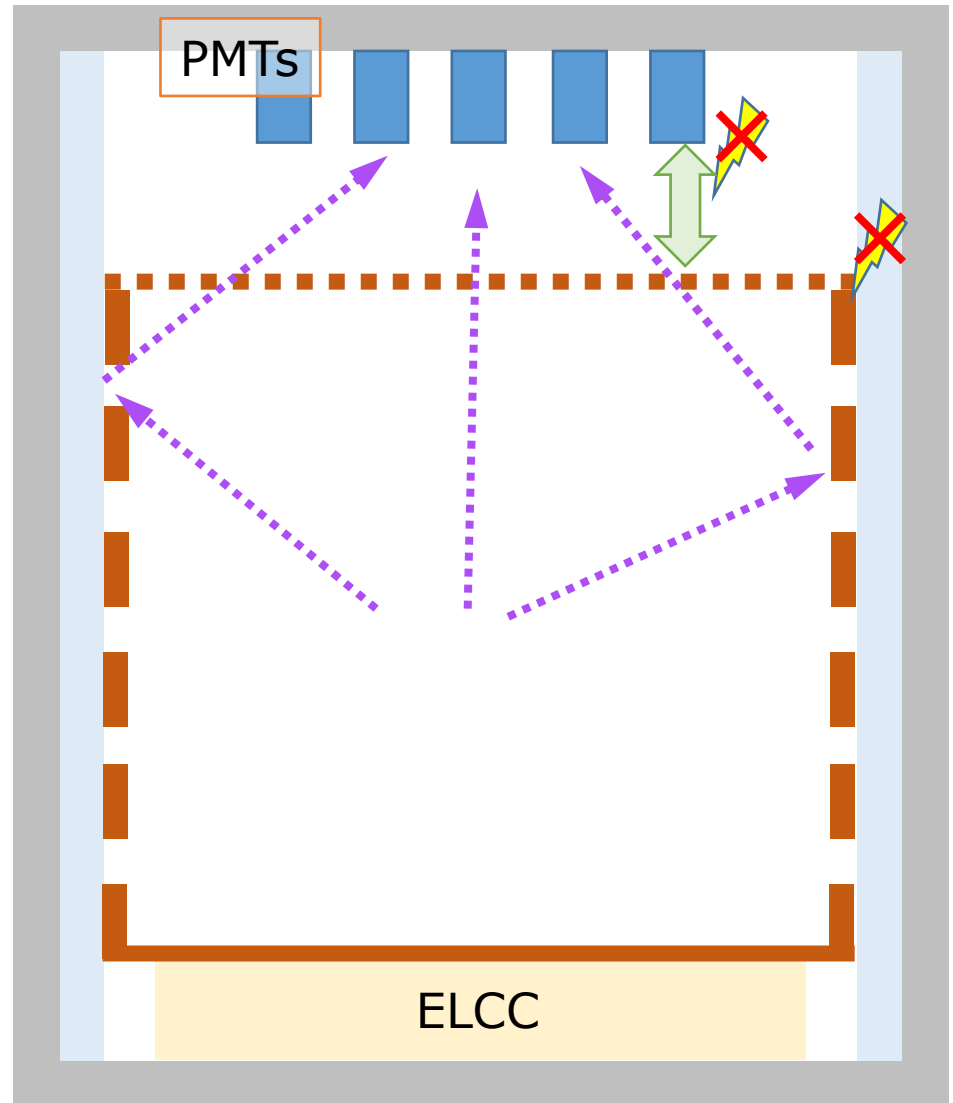
- **0.1 kV/cm/atm  $\pm 5\%$**

No discharge:

- insulation
- take distance

VUV Reflection:

- PTFE or Aluminum

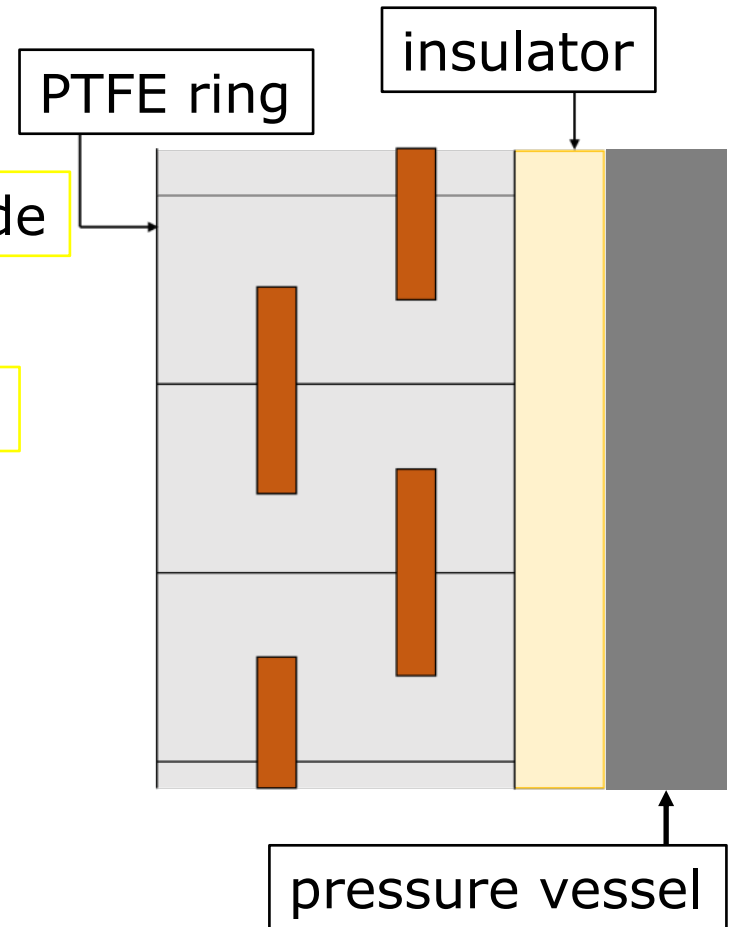
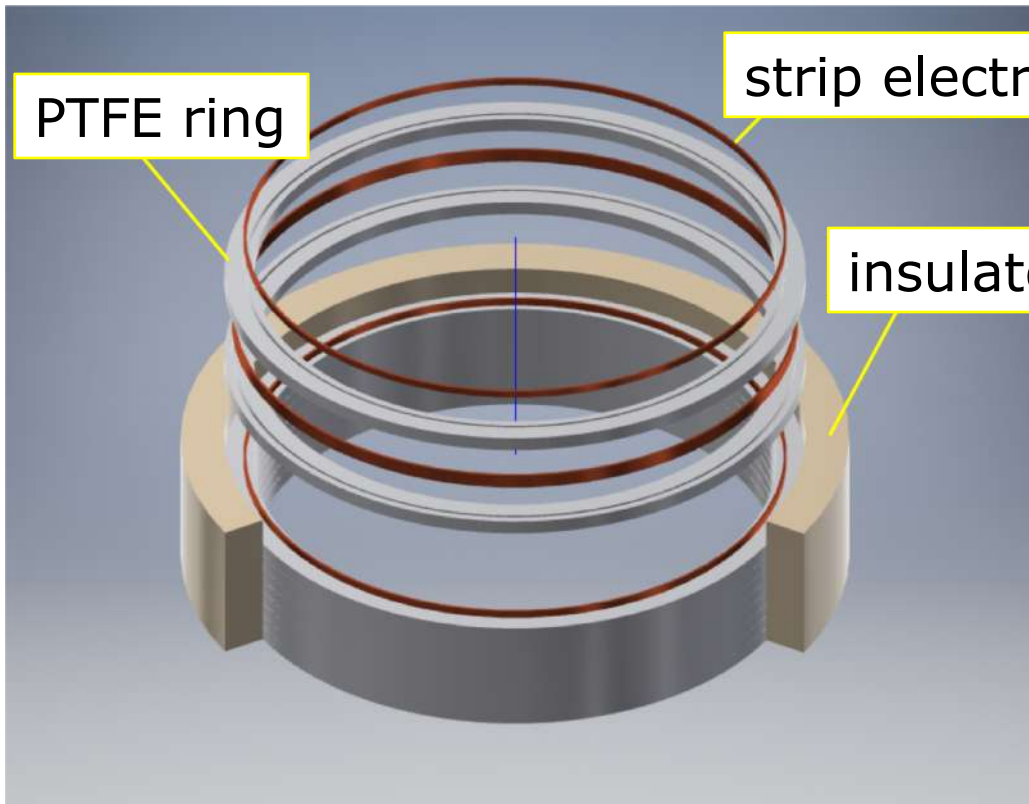


# Current Design

Cause of field distortion = pressure vessel (0 V) → Electric shielding

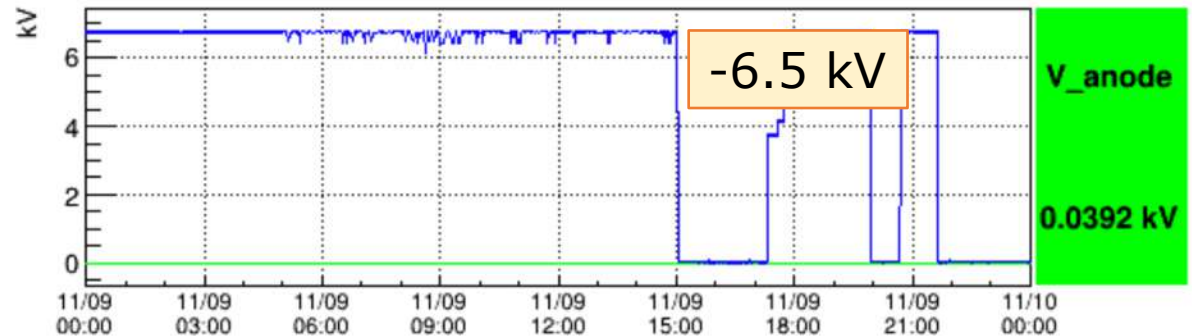
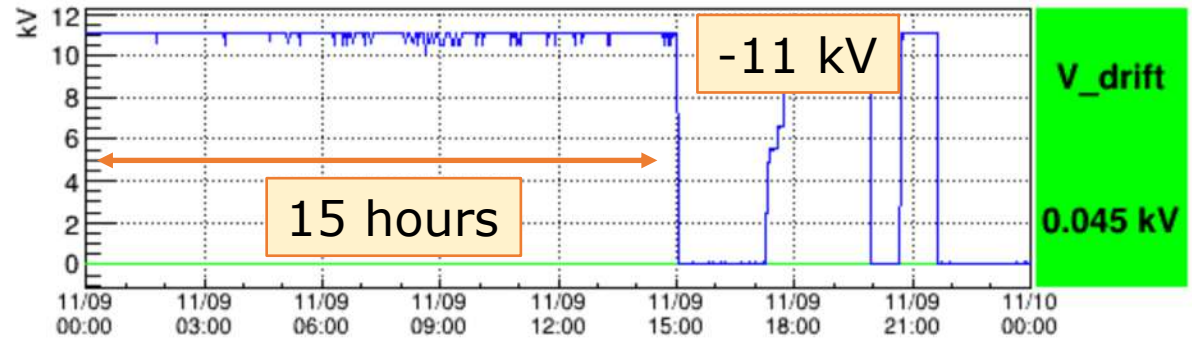
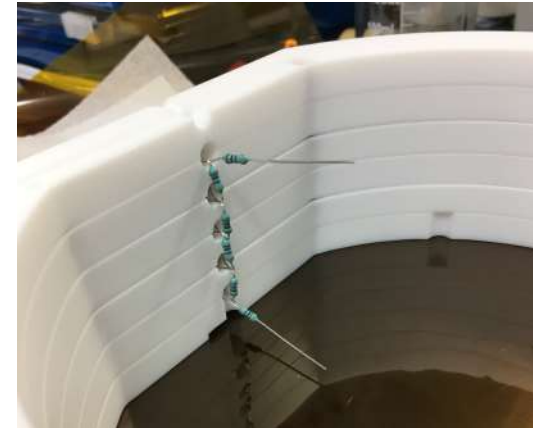
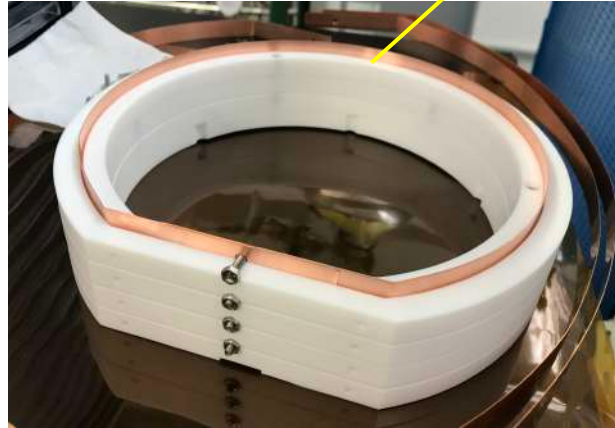
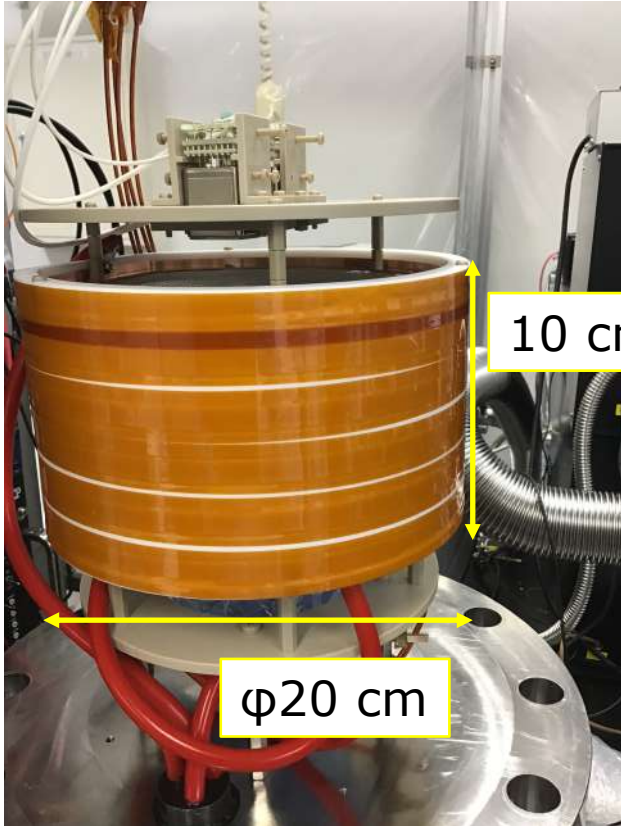


**Double strip electrodes**



# 10-L prototype

0.3 mm thick

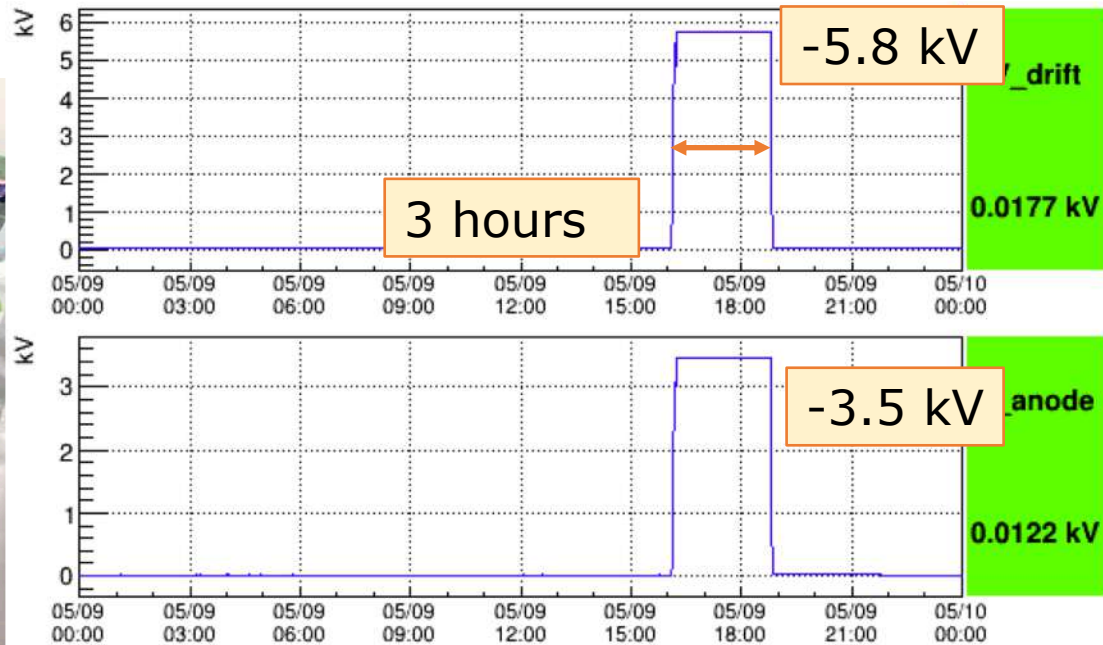
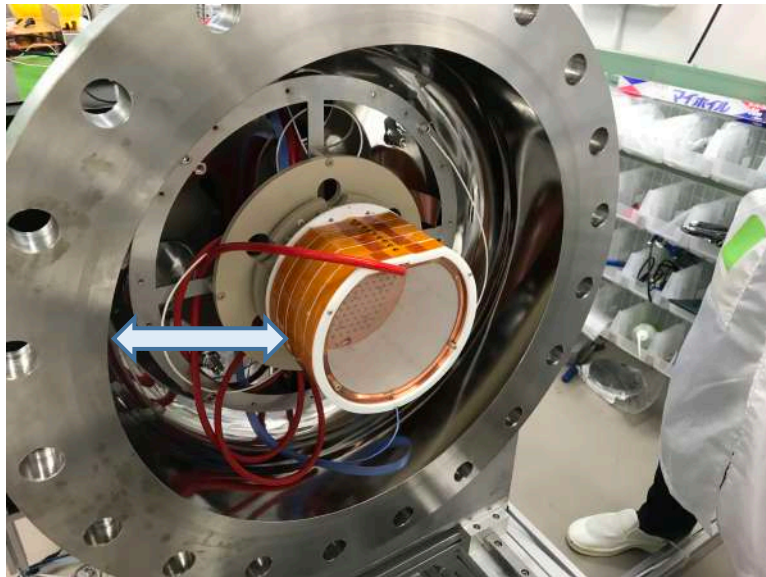


No discharge

- @6 atm
- $E_{EL} = 2.2 \text{ kV/cm/atm}$
- $E_{drift} = 75 \text{ V/cm/atm}$

# 180-L prototype

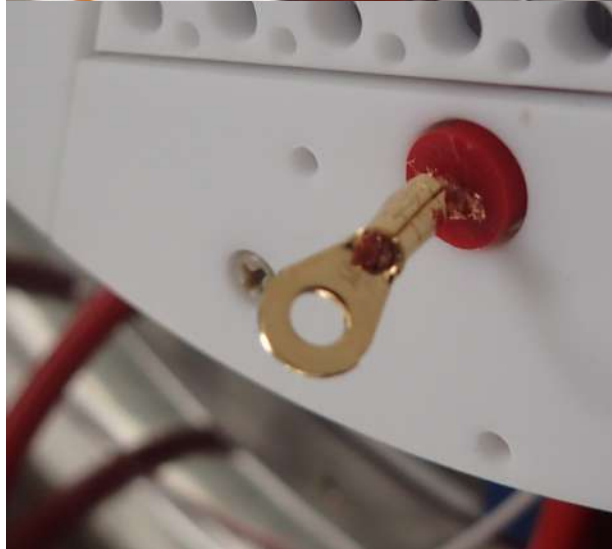
- For now, field cage is 10-L size.....
  - ✓ The pressure vessel is far. → Less probability of discharge
- No discharge
  - ✓ @2.3 atm
  - ✓  $E_{EL} = 3 \text{ kV/cm/atm}$ ,  $E_{drift} = 100 \text{ V/cm/atm}$  (Design Value!)





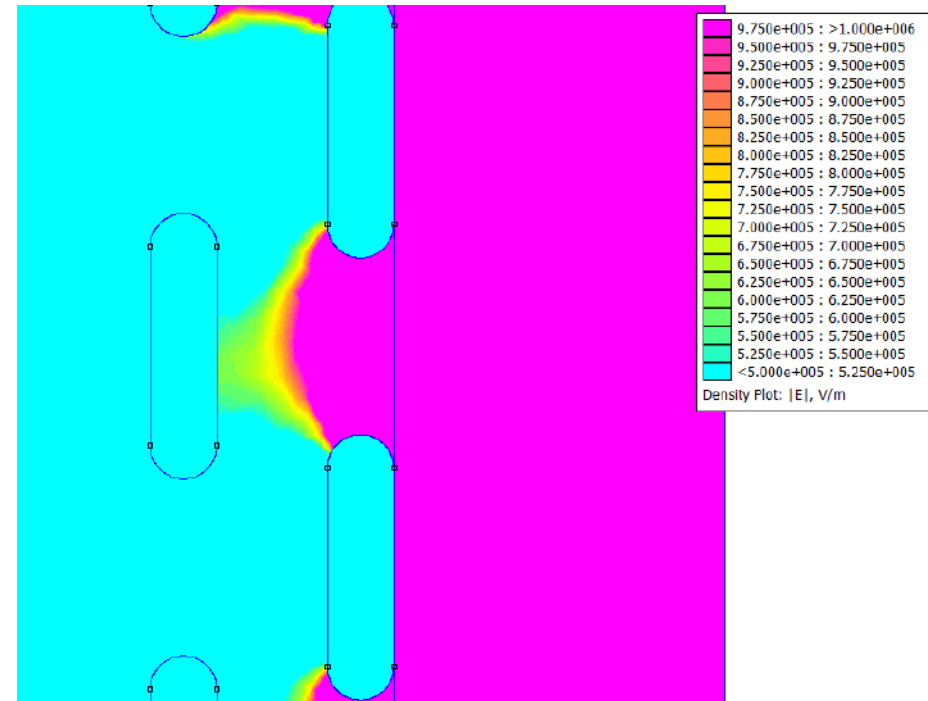
# 180-L prototype

- At 4 atm, discharge occurred at anode 5 kV. ( $E_{EL} = 2.5 \text{ kV/cm/atm}$ )
- Between anode **HV supplying cable** and **ELCC GND mesh**?
- Bending GND mesh will work.
- Cathode and field cage electrodes  $\rightarrow$  No problem



# For 180 L Full Size

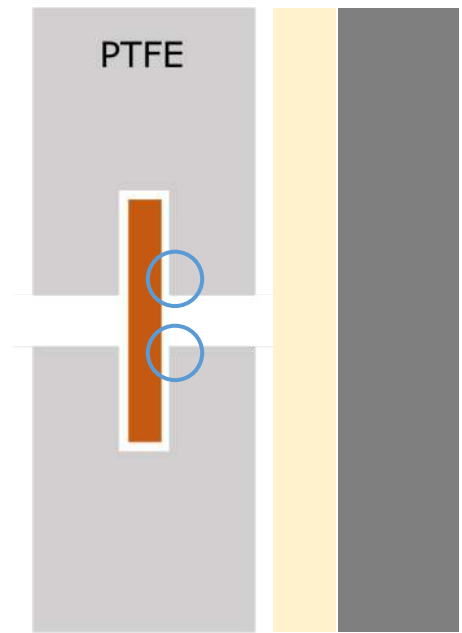
1. Electrode: 0.3 mm  $\rightarrow$  3 mm, rounded off  
✓ No corona discharge



# For 180 L Full Size

## 2. remove PTFE

- ✓ No triple junctions
- ✓ No charge up
- ✓ less material → less BG

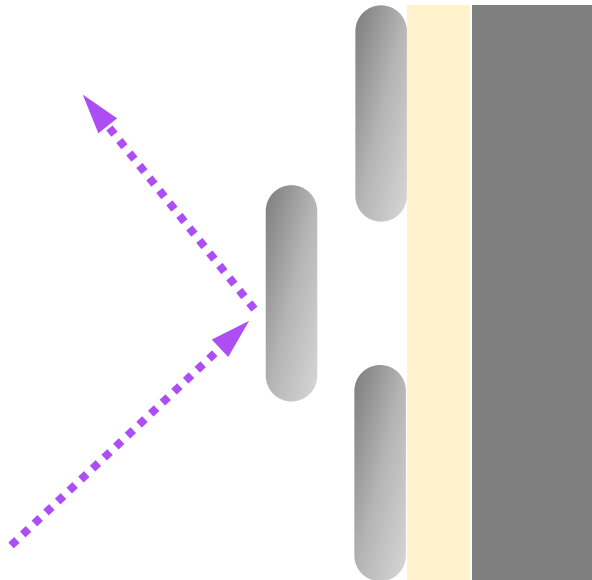


Less scintillation reflection.....

Copper electrode

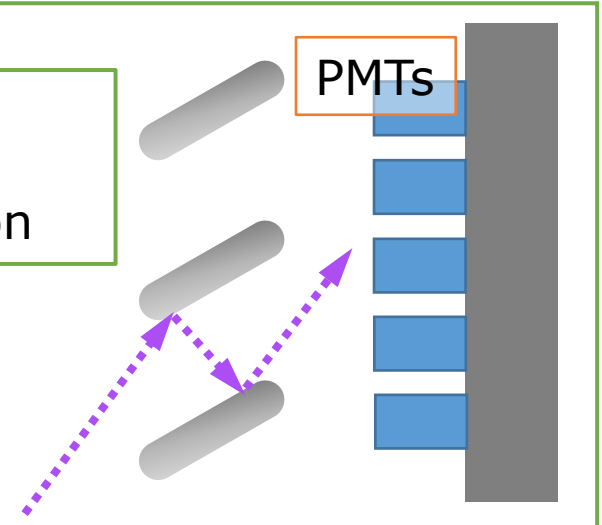


**Mirror finished aluminum!!**



Future option ?

- in case cathode is used for ion-detection



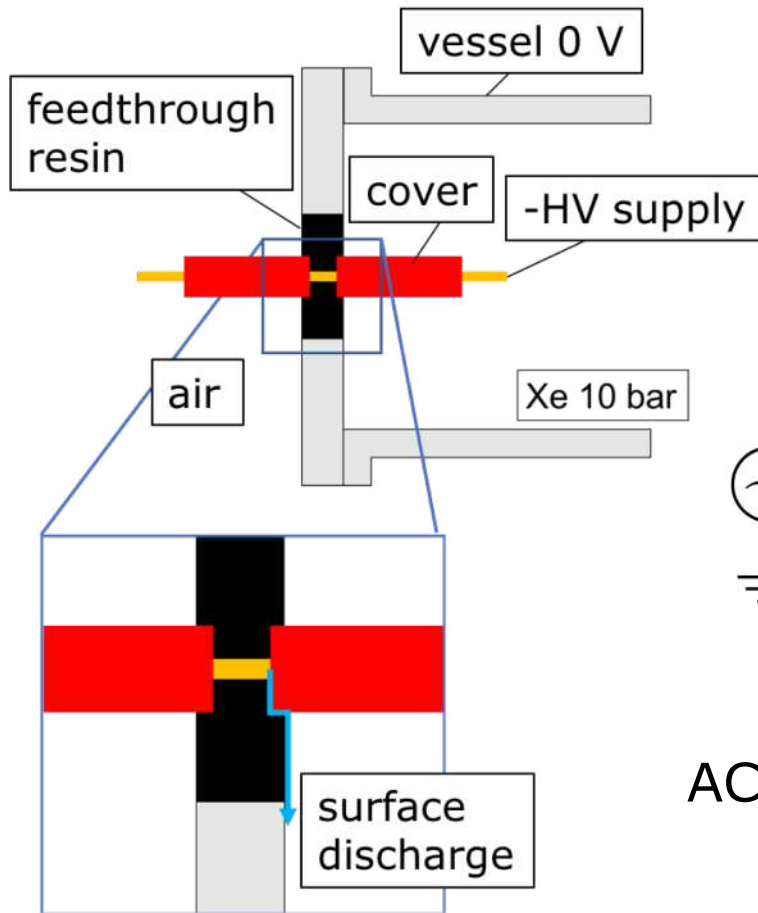


# Cockcroft-Walton Voltage Multiplier

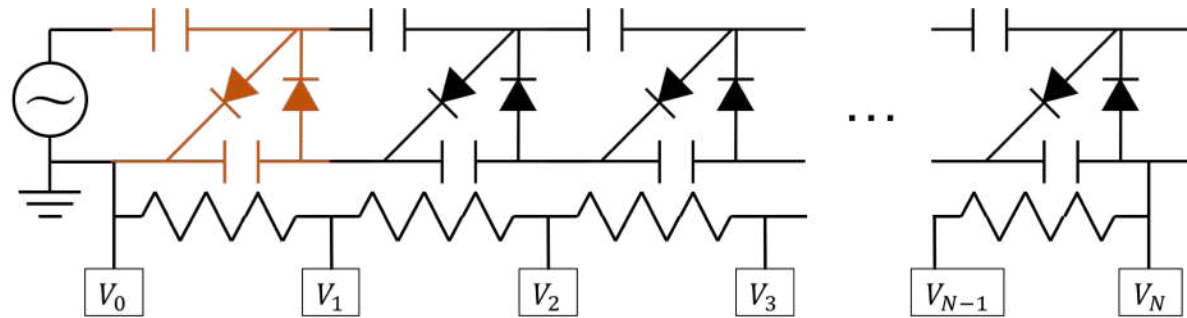
- ✓ FPC CW
- ✓ Output Measurement
- ✓ Frequency Dependence

# HV supply into the vessel

- Direct HV supply → **Surface discharge** at feedthrough



Generate HV in the vessel with Cockcroft-Walton (CW) voltage multiplier



AC input; **p-p  $2U$**  → DC output;  **$2NU$**   
(ideal)

# Voltage Deterioration

- Main cause of output deterioration
  - Output current

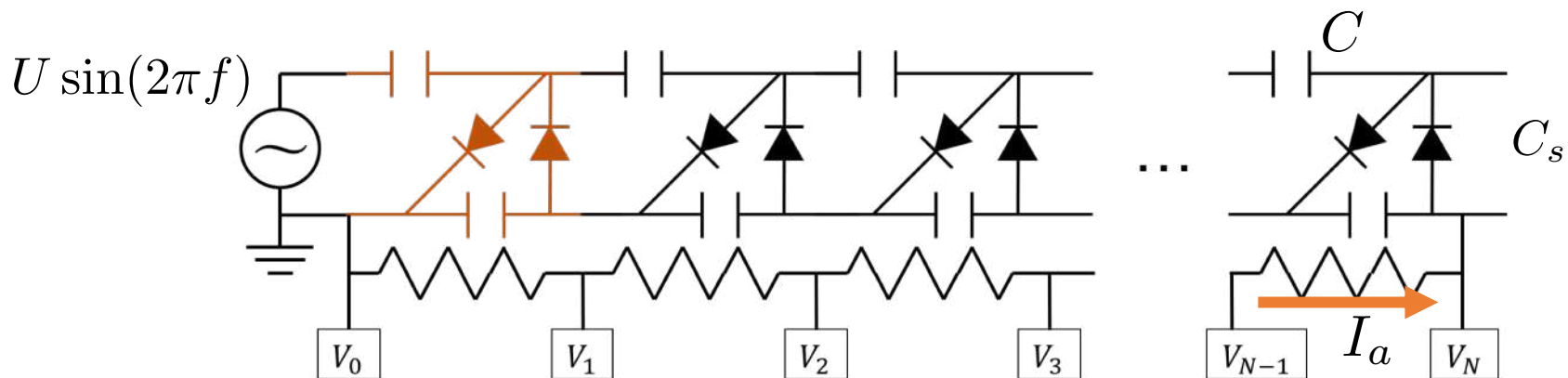
$$\Delta V \simeq \frac{2}{3} \frac{I_a}{fC} N^3$$

- Shunt capacitance of diodes

$$F = \frac{\sqrt{C/C_s}}{2N} \tanh \frac{2N}{\sqrt{C/C_s}}$$

➔  $V_{\text{out}} = F (V_{\text{ideal}} - \Delta V)$

High  $C$ , High  $R$ , High  $f$ , Low  $N$  is important

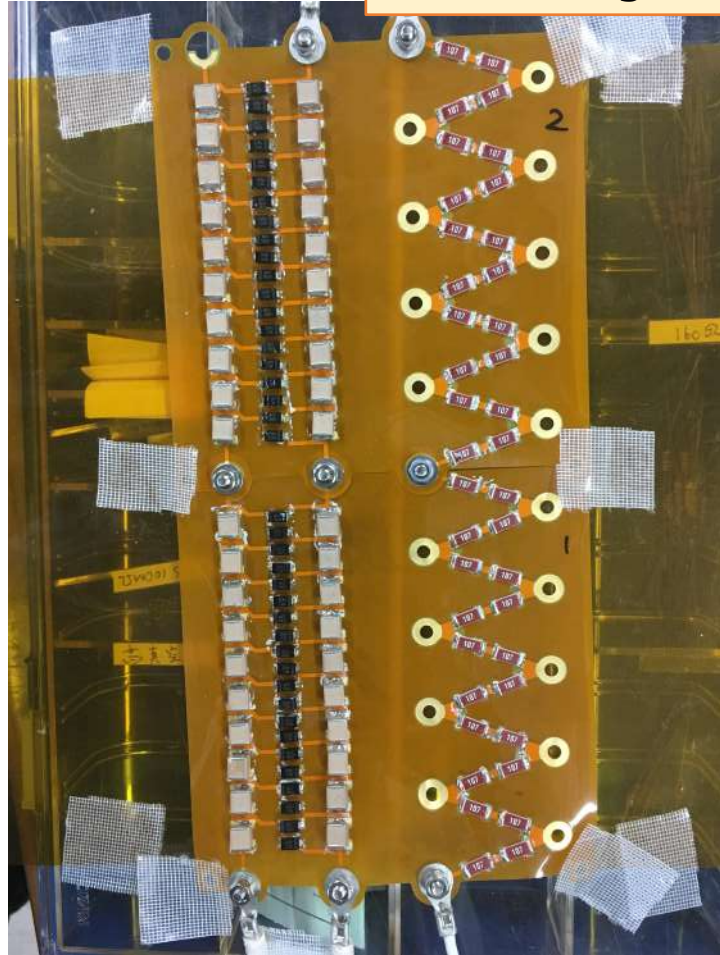
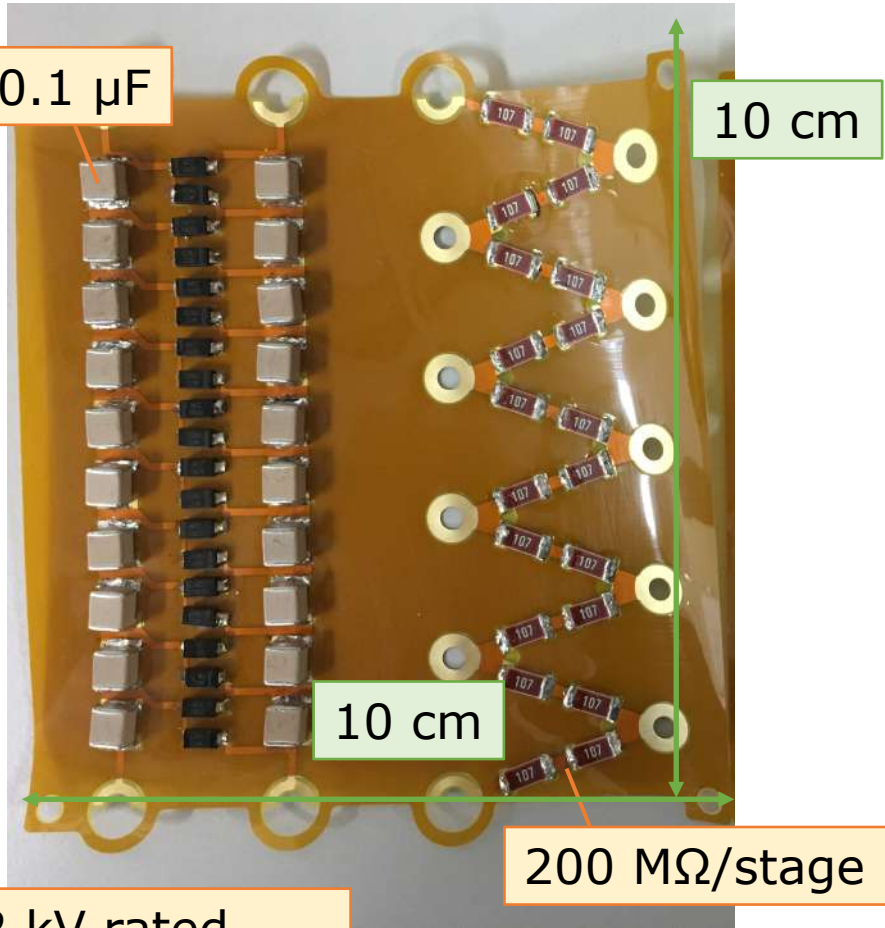


# FPC CW multiplier

Placed in Xe gas → Low outgassing is required

- ✓ Kapton base Flexible Print Circuit(FPC)
- ✓ Vacuum solder

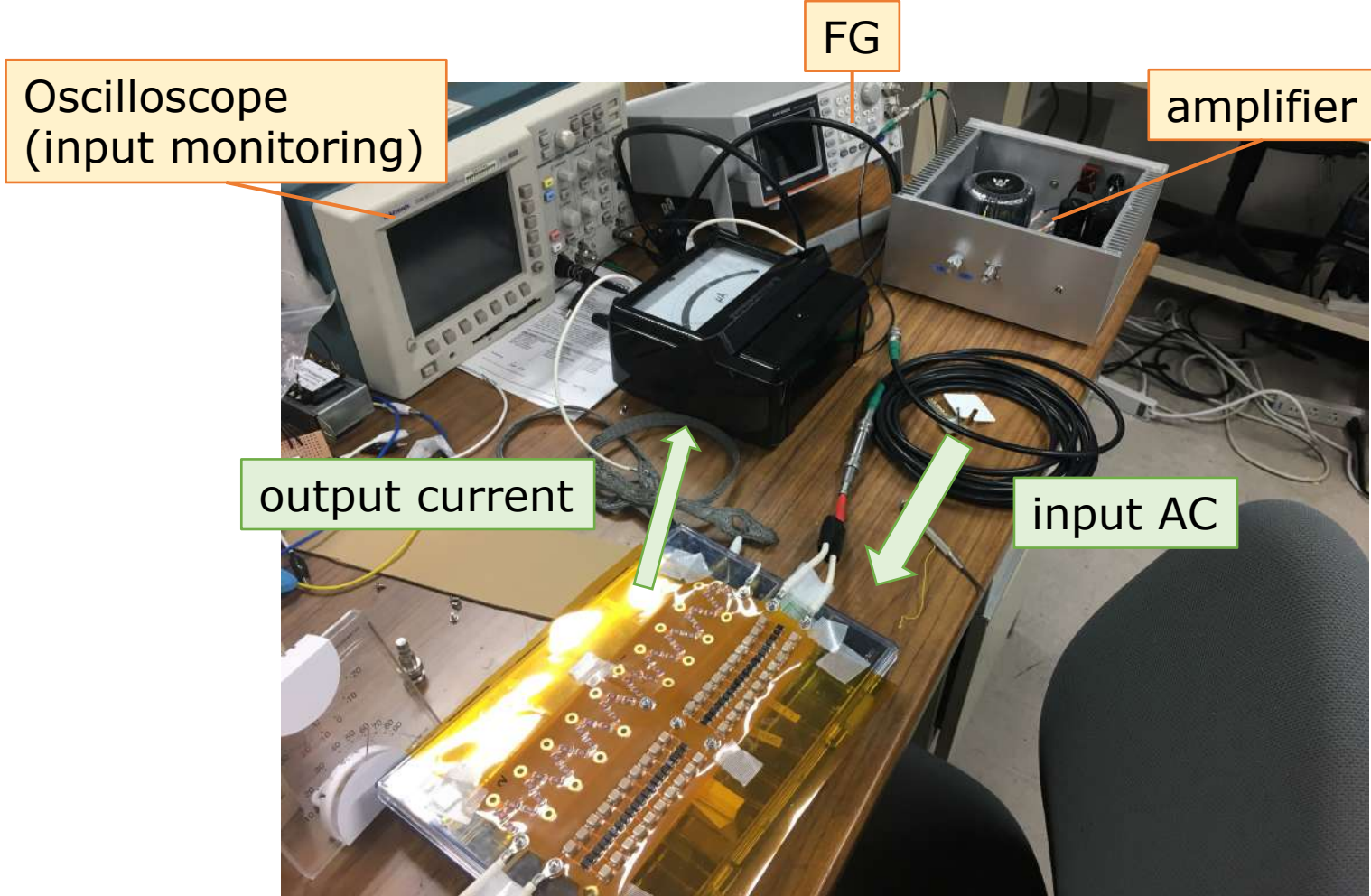
extendable by connecting each other



2 kV rated each elements

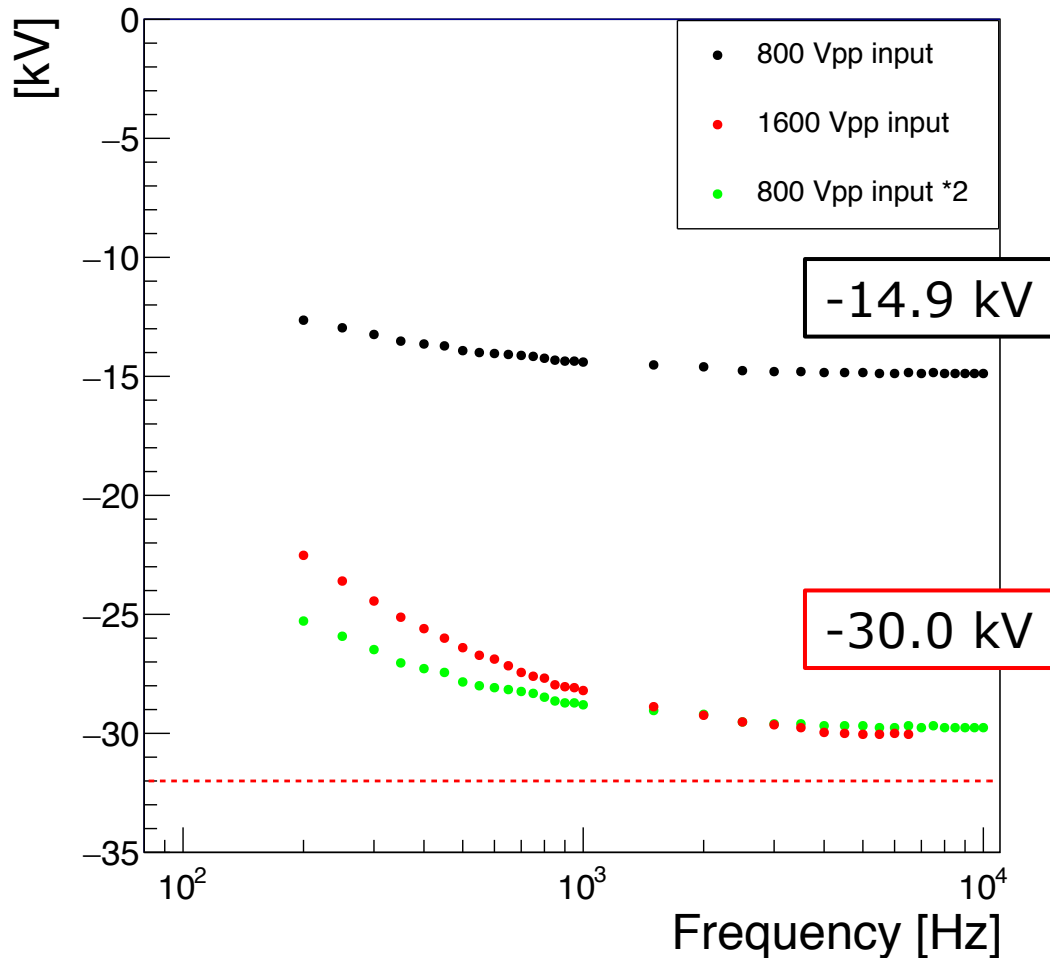
# Output Measurement

Function generator (AC generation;  $V_{pp} < 2\text{ V}$ )  
→ amplifier (gain  $\sim 1000$ ) → CW → ammeter



# Frequency Dependence

Output Voltage



- ✓ 20-stage CW
- ✓ 800 Vpp & 1600 Vpp input
- ✓ ideal output;  
-32 kV @ 1600 Vpp input

- 1/f components is worse for 1600 Vpp input case  
→ more leak current?
- flat @ >4 kHz

Expectation;  
-65 kV is available

- ✓ 50-stage CW
- ✓ ~1800 Vpp
- ✓ 10 kHz



# Summary

- Target;  $E_{EL} = 3 \text{ kV/cm/atm}$ ,  $E_{drift} = 100 \text{ V/cm/atm}$ 
  - ➔  $V_{anode} = -15 \text{ kV}$ ,  $V_{cathode} = -65 \text{ kV}$
- Drift Field Cage
  - ✓ Shaping strong & uniform field  $100 \text{ V/cm/atm} \pm 5\%$
  - ➔ **Double strip electrodes**
- 10-L size field cage is stable w/o discharge.
- Cockcroft-Walton Voltage Multiplier
  - ✓ Achieved  $-30 \text{ kV}$  @ 20 stages,  $1600 \text{ Vpp}$   $4 \text{ kHz}$
  - ✓  $-65 \text{ kV}$  is available @ 50 stages,  $1800 \text{ Vpp}$   $10 \text{ kHz}$